



P/2850-91

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

New York, New York

Masashi UEDA et al.

Date: January 20, 2004

Serial No.: 10/725,905

Group Art Unit: ---

Filed: December 1, 2003

Examiner: ---

For: METHOD AND APPARATUS FOR FORMING THIN FILMS, METHOD FOR
MANUFACTURING SOLAR CELL, AND SOLAR CELL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUBMISSION

Sir:

Submitted herewith is a copy of art together with a form listing the same for the
convenience of the Examiner.

I hereby certify that this correspondence is being
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Respectfully submitted,

Max Moskowitz

Name of applicant, assignee or
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Signature
January 20, 2004

Date of Signature

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Enclosures

APPLICANT'S ART CITATION (Use several sheets if necessary)		Application 10/725,905		OFGS File No. P/2850-91		
		Applicant Masashi UEDA et al.				
		Filing Date December 1, 2003		Group Art Unit ---		
U.S. PATENT DOCUMENTS						
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub- class	Filing Date If Appropriate
	US-5,632,821	05-1997	Doi	134	1.1	
	US-					
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FOREIGN PATENT DOCUMENTS						
	Document Number	Date MM-YYYY	Country	Class	Sub- class	Translation Yes No
	2000-252496	09-2000	Japan			X
	2003-109798	04-2003	Japan			X
	WO 01-19144 A1	03-2001	PCT			X
	06-283430	10-1994	Japan			X
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
	Tomoko Takagi, U.S. Patent Application Serial No. 10/276,371, filed May 17, 2001 entitled "PLASMA CVD APPARATUS AND METHOD"					
Examiner			Date Considered			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.						